

**Homework 5**

1. You have a task with execution time,  $T$ . You take  $N$  checkpoints, equally spaced through the lifetime of that task. The overhead for each checkpoint is  $T_{ov}$  and  $T_{lt} = T_{ov}$ . Given that during execution, the task is affected by a total of  $k$  point failures (i.e., failures from which the processor recovers in negligible time).

(a) What is the maximum execution time of the task?

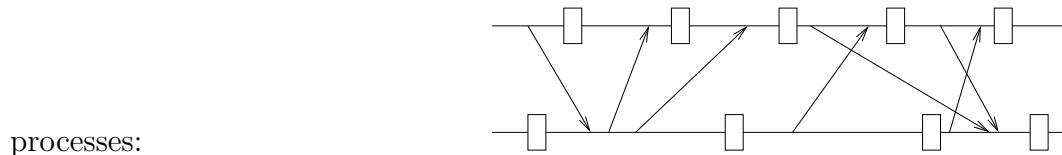
(b) Find  $N$  such that this maximum execution time is minimized. It is fine to get a non-integer answer (say  $x$ ): in practice, this will mean that you will pick the better of  $\lfloor x \rfloor$  and  $\lceil x \rceil$ .

2. Solve the equation  $e^{\lambda(T_{ex}+T_{ov})} = \frac{1}{1-\lambda T_{ex}}$  numerically and compare the calculated  $T_{ex}^{opt}$  to the value obtained in

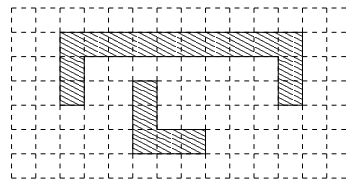
$$T_{ex}^{opt} = \sqrt{\frac{2T_{ov}}{\lambda} + 2T_{ov} \left( T_r + T_{lt} - \frac{T_{ov}}{2} \right)}$$

for the simpler model. Assume  $T_r = 0$  and  $T_{lt} = T_{ov} = 0.1$ . Vary  $\lambda$  from  $10^{-7}$  to  $10^{-2}$ .

3. Identify all the consistent recovery lines in the following execution of two concurrent



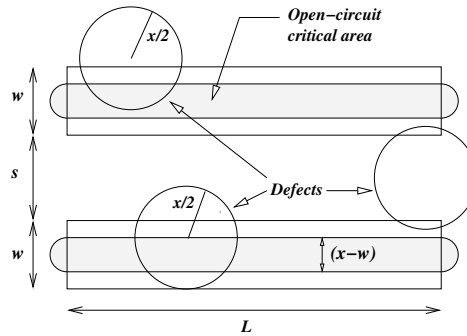
4. Use the polygon expansion technique to calculate approximately the critical area for circular short-circuit defects of diameter 3 for the  $14 \times 7$  layout consisting of two conductors



shown below.

5. (a) Derive an expression for the critical area  $A_{miss}^{(c)}(x)$  of a circular missing-material defect with diameter  $x$  in the case of two conductors of length  $L$ , width  $w$  and separation  $s$  (as shown in the figure below). Ignore the non-linear terms, and note that

the expression differs for the three cases:  $x < w$ ;  $w \leq x \leq 2w + s$ ; and  $2w + s < x \leq x_M$ .



(b) Find the average critical area  $A_{miss}^{(c)}$  using the defect size distribution in the equation

$$f_d(x) = \begin{cases} kx^{-p} & \text{if } x_o \leq x \leq x_M \\ 0 & \text{otherwise} \end{cases}$$

with  $p = 3$ . For simplicity, assume  $x_M = \infty$ .

6. A chip with an area of  $0.2 \text{ cm}^2$  (and no redundancy) is currently manufactured. This chip has a POF of  $\theta = 0.6$  and an observed yield of  $Y_1 = 0.87$ . The manufacturer plans to fabricate a similar but larger chip, with an area of  $0.3 \text{ cm}^2$ , using the same wafer fabrication equipment. Assume that there is only one type of defects, and that the yield of both chips follows the Poisson model  $Y = e^{-\theta A_{chip} d}$  with the same POF  $\theta$  and the same defect density  $d$ .

(a) Calculate the defect density  $d$  and the projected yield  $Y_2$  of the second chip.

(b) Let the area of the second chip be a variable  $A$ . Draw the graph of  $Y_2$ , the yield of the second chip, as a function of  $A$  (for  $A$  between 0 and 2).

7. A chip of area  $A_{chip}$  (without redundancy, and with one type of defects) is currently manufactured at a yield of  $Y = 0.9$ . The manufacturer is examining the possibility of designing and fabricating two larger chips with areas of  $2A_{chip}$  and  $4A_{chip}$ . The designs and layouts of the new chips will be similar to those of the current chip (i.e., same  $\theta$ ), and the defect density  $d$  will remain the same.

(a) Calculate the expected yields of the two new chips assuming a Poisson model.

(b) Calculate the expected yields of the two new chips assuming a Negative Binomial model with  $\alpha = 1.5$ .

(c) Discuss the difference between the results of (a) and (b).